

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventors: Blaine R. Spady; John D. Heaton
 Assignee: Nanometrics Incorporated
 Title: Metrology/Inspection Positioning System
 Serial No.: 09/458,123 Filing Date: December 8, 1999
 Examiner: Philip Sana Natividad Group Art Unit: 2877
 Docket No.: NAN035 US Confirmation No.: 8470

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RESPONSE TO RESTRICTION REQUIREMENT

Dear Sir:

In Response to the Office Action dated December 16, 2002, Applicants elect without traverse to have the invention of Group I, Claims 1-9, examined. Please withdraw from consideration Claims 10-14, which are drawn to the invention of Group II. Applicants reserve the right to seek examination of the invention of Group II in a divisional application.

It is believed that no fees are due. Nevertheless, if the Patent Office determines that an extension and/or other relief is required, Patent Owner petitions for any required relief including extensions of time and authorizes the Assistant Commissioner to charge the cost of such petitions and/or other fees due in connection with this filing of this document to Deposit Account No. 50-2263 referencing NAN035 US.

Should the Examiner have any questions concerning this response, the Examiner is invited to call the undersigned at (408) 982-8200, ext. 2.

CERTIFICATE OF FACSIMILE TRANSMISSION

I hereby certify that this correspondence is being facsimile transmitted to the U.S. Patent and Trademark Office to the fax number 703-872-9318 on January 13, 2003.

Michael J. Halbert 1-13-03

Attorney for Applicant(s)

Date of Signature

Respectfully submitted,

Michael J. Halbert
 Michael J. Halbert
 Attorney for Applicant(s)
 Reg. No. 40,633

SILICON VALLEY
 PATENT GROUP LLP
 2350 Mission College Blvd.
 Suite 300
 Santa Clara, CA 95054
 (408) 982-8200
 FAX (408) 982-8210